



In re Application of:  
Cheung, et al.

Group Art Unit: Unknown

**Examiner:** Unknown

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For: Plasma Processes For  
Depositing Low Dielectric  
Constant Films

**CERTIFICATE OF MAILING**  
**37 CFR 1.8**

I hereby certify that this correspondence is being deposited on 12/12, 2003 with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.

12/12/03  
Date

John A. Jones  
Signature

**Dear Sir:**

Prior to examination, please amend the above-identified application as follows. The Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/AMAT/3032.C6/KMT the fee of \$54.00 for 3 additional claims.

Amendments to the Claims begin on page 2. Remarks begin on page 6.